# Overview of Digital Pixel Test Structure (DPTS) studies at LBNL

Barak Schmookler

O(10 µm)

#### ALPIDE Chip



15 µm NWELL COLLECTION NMOS PMOS ELECTRODE PWELL PWELL NWELL NWELL DEEP PWELL DEEP PWELL LOW DOSE N-TYPE IMPLANT 1.25 µm .25 µm P<sup>=</sup> EPITAXIAL LAYER P<sup>+</sup> SUBSTRATE

- The most complex prototype MAPS produced in the first submission of the Tower Partners Semiconduction Company 65nm technology process.
- Junction displaced into the epitaxial layer to deplete layer over the full pixel width.

#### **DPTS Chip**

#### Chip on carrier card







- The DPTS chip is controlled by a set of external reference currents and voltages.
- > It is read out via a current mode logic (CML) output.
- The in-pixel front end amplifies, shapes, and discriminates the signal from the collection diode.
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1. DPTS chip and carrier card



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- 2. Proximity board



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- 3. MLR1 DAQ board



- 1. DPTS chip and carrier card
- 2. Proximity board
- 3. MLR1 DAQ board
- 4. Power supply and digital oscilloscope

#### Threshold scan



At a given  $V_H$  (i.e. injected charge), each pixel is pulsed 25 times and the number of hits is recorded. A hit requires two pulses to be captured by the scope – indicating the assertion and de-assertion of the discriminator pulse.



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### Threshold scan



The threshold and noise can be determined from the S-Curve.

#### Threshold scan



We can control the threshold by adjusting the VCASB voltage.



#### Time-over-threshold (ToT)



The ToT increases linearly with the total collected (injected) charge.

We observe a large pixel-to-pixel variation, which we hope to understand. See next talk by Oscar!

#### Pixel position decoding



In the case where we don't inject charge, we need a way to decode the pixel that fired based on the CML signal. This is encoded in the PID and GID times.



#### Fake hit rate check



### <sup>55</sup>Fe source data



Collected 100k triggers with a <sup>55</sup>Fe source. After requiring events with a single pixel and applying some other cuts, about 40k events remain.

The main peak should be the K-alpha X-ray at 5.9 keV. Since it takes 3.6 eV to create an electron-hole pair in silicon, we would expect this peak to be at 1640 electrons. However, we see the peak at ~1510 electrons. Why do we see this shift?



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The ToT calibration is based on the injected charge (set by the voltage  $V_H$ ). The  $C_{inj}$  capacitance can differ from the design value.

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# Summary

- >We have a working bench setup for the DPTS prototype chip.
- ➤We have done some basic studies with injected charge to test the front-end electronics.
- ≻We have also collected data using and <sup>55</sup>Fe source.
- We are currently focusing on studying the pixel-to-pixel variation of the ToT. See next talk by Oscar!